

IPW

Attorney's Docket No.: 42P17283

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Michael McSwiney et al.

U.S. Serial No: 10/750,062

Filed: December 30, 2003

For: METHOD AND APPARATUS FOR LOW
TEMPERATURE SILICON NITRIDE DEPOSITION)

Examiner: Turocy, David P.

Art Unit: 1762

Commissioner of Patents and Trademarks
P.O. Box 1405
Alexandria, VA 22313-1450

RESPONSE TO ELECTION REQUIREMENT

Sir:

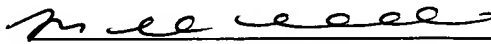
In response to the Election Requirement mailed February 23, 2007, applicant(s) hereby elects to prosecute Group I claims 1-20, drawn to a method for depositing a silicon film. As such, applicant(s) elects to withdraw Group II claims 21-27, drawn to coating an apparatus.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN

Date: March 5, 2007


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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, PO Box 1450, Alexandria, Virginia 22313-1450

on March 5, 2007
Date of Deposit
TERESA MITCHELL
Name of Person Mailing Correspondence
Teresa Mitchell 3/5/07
Signature Date